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Application No.: 09/778,245

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First Named Inventor: Shing Lee et al.

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TECHNOLOGY CENTER 2800

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Examiner: Hoa Q. Pham

Atty. Docket No.: M-10685-1C US

Title: System For Measureing Polarimetric Spectrum and Other Properties of a Sample

Assignee: KLA-Tencor Corporation

San Francisco, California  
January 22, 2003

BOX RCE  
COMMISSIONER FOR PATENTS  
Washington, D. C. 20231

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97, and 1.98, Applicant(s) call(s) the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application.

All copies of the documents listed are enclosed.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or (3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

The Commissioner is authorized to charge any fees that may be required, or to credit any overpayment, against Deposit Account No. 19-2386.

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